Electronic Supplementary Information

Enhancing chemisorption efficiency and thin-film characteristics via discrete feeding method in highk dielectric atomic layer deposition for preventing interfacial layer formation

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Figure S1. Ti 2p spectra for (black) TiN substrate, (red) TiN / -nm-thick-ZrO₂ (deposited by TEMAZ_{base}), and (blue) TiN / 3-nm-thick-ZrO₂ (deposited by TEMAZ_{DFM}).